

Vacuum Science and Technology for Accelerator Vacuum Systems

Yulin Li and Xianghong Liu Cornell University, Ithaca, NY







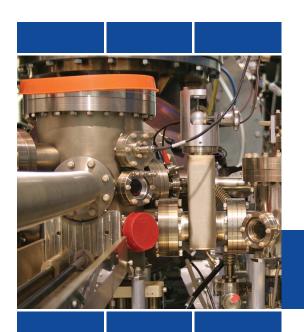


Table of Contents

- Vacuum Fundamentals
- Vacuum Instrumentation
- Vacuum Pumps
- Vacuum Components/Hardware
- Vacuum Systems Engineering
- Accelerator Vacuum Considerations, etc.

January 14-18 2013 2

SESSION 5: Vacuum System Engineering

- > Typical vacuum system design/engineering flow
- > High vacuum system design considerations
- > Ultrahigh vacuum system design considerations
- > Tools for vacuum system engineering
- Vacuum system integration

Typical Vacuum System Design Flow



Process Requirements and Specifications (beam current, cathode lifetime, spatial boundary, etc.)

Vacuum Requirements

(base pressure, dynamic pressure limit, p. pressure limit, system up-time, etc.)

Mechanical Design

(material selections, vacuum envelope, pumping system, etc.)

Design Validations

(mech. & thermal stress analysis, pressure calculations, Prototype and tests, etc.)

Value Engineering and Design Optimization

(cost reduction, vendor selections, etc.)





Accelerator Vacuum Design Considerations



- ☐ Particle beam parameters
 - \rightarrow Type of particles: e^- , e^+ , p^+ , ions, etc.
 - → Beam density
 - → Beam temporal and spatial properties, etc.
 - **→** ..., ...
- ☐ Magnets Mainly spatial constraints
- □ Accelerating RF cavities
 - → Particulate control ultra-clean vacuum systems
 - → 'Free' cryo-pumping for SRFs, but handling of warm-ups
 - → Cryo related issues (insolation vacuum, etc.)
- ☐ Key functional accelerator components
 - → SR generation insertion devices in-vacuum and/or ex-vacuum
 - → Particle sources electron and positron, protons, ions,
 - → Beam instrumentations BPMs, beam size monitors, etc.



Vacuum Pressure Considerations



1. Base pressure

- → For e^-/e^+ storage rings, base pressure usually an order of magnitude below beam induced dynamic pressure, typically in the low 10^{-10} torr range → For high intensity proton and heavy ion machines, there are more demanding requirements on the base pressure, as beam-gas interaction is much sensitive
- → For some special devices, such as photo-cathode electron sources, XHV environment is essential for the cathode lifetime

2. Dynamic pressure

- \rightarrow For e⁻/e⁺ storage rings, the dominating dynamic pressure is due to photon-induced desorption from intense SR. The maximum pressure must be controlled to a level such that the beam-loss from beam-gas interaction is below the other factors.
- \rightarrow For p^+ and ion machines, SR usually negligible. The dynamic pressure rise is primarily due to lost particles. Though beam loss is small, proton/ion induced desorption is much higher than PSD.
- → Other collective effects (such as electron cloud, HOM heating, etc.) may also induce (usually nonlinear) pressure rises.





High Vacuum Systems



- \Box High vacuum system is dynamic pressure in range of 10-6 to 10-9 torr
- ☐ Examples of accelerator high vacuum systems:
 - → Low beam intensity LINACs
 - → Low beam intensity energy booster rings for storage rings
 - → Insolation vacuum for cryo-modules
- ☐ For these systems, often discrete pumps are sufficient. Typical pumps used are ion pumps, diffusion pumps, cryo-pumps and turbo-molecular pumps.
- ☐ For cryo-module insolation vacuum, though with 'build-in' cryopumping from cryogenic surfaces, sufficient contingency pumping system must always included to deal with possible internal helium leaks.
- ☐ Material selection for high vacuum systems is usually dictated by cost and easiness of fabrications. Though cleanness is not as critical, a clean system will reduce cost of pumping system.



Ultra-High Vacuum Systems



- \Box UHV system is dynamic pressure in range below 10-9 torr
- ☐ Examples of accelerator UHV systems:
 - → Electron storage rings for light sources and colliders
 - → High intensity proton and ion machines
 - → High intensity LINACs
- ☐ For these systems, often distributed pumps are needed with gas conductance limited beam chambers, and distributed dynamic gas load. Only UHV-compatible pumps should be used, including ion pumps, NEGs and TiSPs.
- ☐ In most cases, only UHV compatible metals should be used for these systems. Stringent cleaning and UHV-compatible handling is paramount. Only all-metal joints are permitted.
- ☐ UHV ion gauges must be included in the UHV system. RGAs are strongly recommended for vacuum diagnostics.
- UHV system roughing and venting needs significant cares.



Beam Chamber Materials — Electric and Thermal



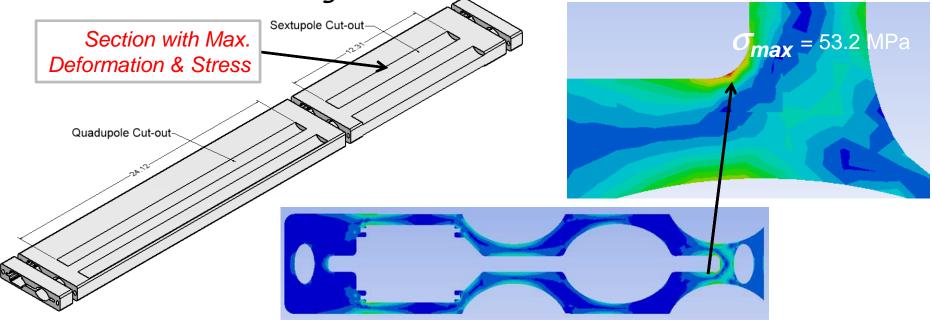
- □ For high beam intensity accelerators, beam pipe material with high electric conductivity must be used for carrying image wall current.
- □ For beam chambers not subject to direct power deposition from synchrotron radiation or particle bombardment, stainless steel with copper coating/plating/lining is an option. The thickness of the copper coating only need to be a few factor of skindepth at fundamental beam RF frequency.
- ☐ For beam chambers intercept SR power, or intense particle impingement, material with good bulk electric and thermal conductivities must be used. Aluminum alloys, copper or copper alloys are usually used.



Chamber Design - Mechanical Consideration



- ☐ In many beam chamber designs, there are often competing requirements to provide adequate beam aperture, while to bring magnet poles close to particle beam.
- These requirements may lead to minimizing chamber wall thickness and complex chamber shapes. Thorough mechanical analysis of chamber stress under atmospheric pressure must be carried out. Commercial finite-element analysis (FEA) tools, such as ANSYS, are used to validate a design.





Mechanical Consideration Cont.

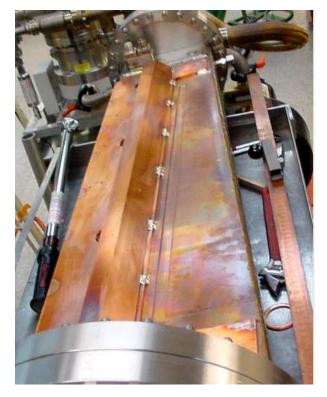


FEA results are not always the final word, if the material property inputs are incorrect (or not available). A copper beam chamber deformed severely during a 150°C bakeout, though FEA results predicted a 'healthy'

safety margin at the temperature!



Distorted copper chamber during a bakeout



The chamber was saved by pressurizing and stiffening





Synchrotron Radiation in e⁻/e⁺ Storage Rings



- ☐ For high beam current electron storage rings, SR power deposited on vacuum walls must be calculated.
- The calculated SR power distribution will be used to evaluate vacuum chamber design, to ensure
 - (1) adequate cooling is provided to keep heating and thermal stress below a safe level;
 - (2) no part of wall is subject to higher SR power that cannot handle by the wall materials;
 - (3) proper 'masks' are in place to shadow components that may be damaged or affected by SR.
- \Box For simple wall profiles, one can use the following formula for linear power density. The area power density can be calculated with a vertical SR angular spread of α_v = 1/ γ , where γ = E_{beam}/E_{rest} .

$$P(W/mA) = 88.5 \frac{E^4 (GeV)}{R(m)} \frac{\Delta \alpha}{2 \pi}$$

Synchrotron Radiation Calculations — SYNRAD



- ☐ For more complex accelerator vacuum wall profile and SR-generating magnet arrangement, computing program is usually employed for SR calculations.
- ☐ In CESR, a program, SYNRAD, integrated into Bmad (A Relativistic Charged Particle Simulation Library REF), is widely used for SR calculations.
- ☐ In SYNRAD, accelerator is divided into element along the curvilinear coordinates:
 - Photons are generated along the length of any element where SR are produced, using standard SR formulas for dipoles, quadrupoles and wigglers.
 - The generated photons are tracked to the vacuum chamber wall, horizontally, both inside and outside walls, also divided into elements.
 - SR power and photon flux along the walls are calculated.

REF: D. Sagan (dcs16@cornell.edu), Synrad Information, October 1, 2010





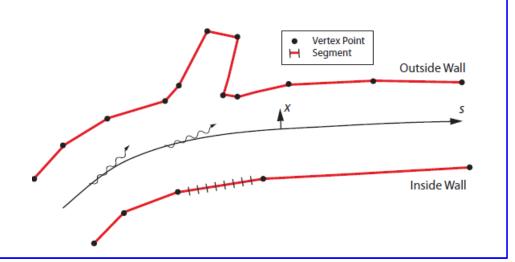
SYNRAD Input files



```
&synrad_params
                                                                       Main Input
  sr_param%lat_file = "lat.bmad"
                                  ! Input lattice.
  sr_param%i_beam = 0.1
                                  ! Single-beam current.
  sr_param%epsilon_v = 10e-12
                                  ! Vertical emittance.
  sr_param%n_slice = 20
                                  ! # of slices per element or wiggler period
  seg_len = 0.1
                                  ! Segment length for calculation.
 beam_direction = 0
                                  ! -1 = track backwards only,
                                  ! 0 = track both directions, 1 = forward.
                                  ! "NONE" => Use a wall with a fixed offset from the bear
 wall file = "wall.dat"
 wall offset = 0.045
                                  ! Used when wall file is set to "NONE"
 forward beam = "POSITRON"
                                  ! "POSITRON" or "ELECTRON"
 backward_beam = "ELECTRON"
                                  ! This is important if there are elsep elements.
```

Wall Definition

```
! Note: x_inside should be negative.
! Note: First s_position should be 0.
!
!s_position x_inside x_outside
0 -0.025 0.025
10 -0.025 0.025
10.3 -0.025 0.037
... etc ...
```







SYNRAD Generated Five Output files



element_power.dat

List of all elements where radiation is produced showing the power radiated and the power that hit the walls. These two numbers should be the same.

synch_power_negative_x_side.dat & synch_power_positive_x_side.dat

List of all wall segments showing such things as power deposited, power per unit length, photons per second impinging, etc.

synrad_negative_x_side.txt
 synrad_positive_x_side.txt
 Similar to above, only in different format





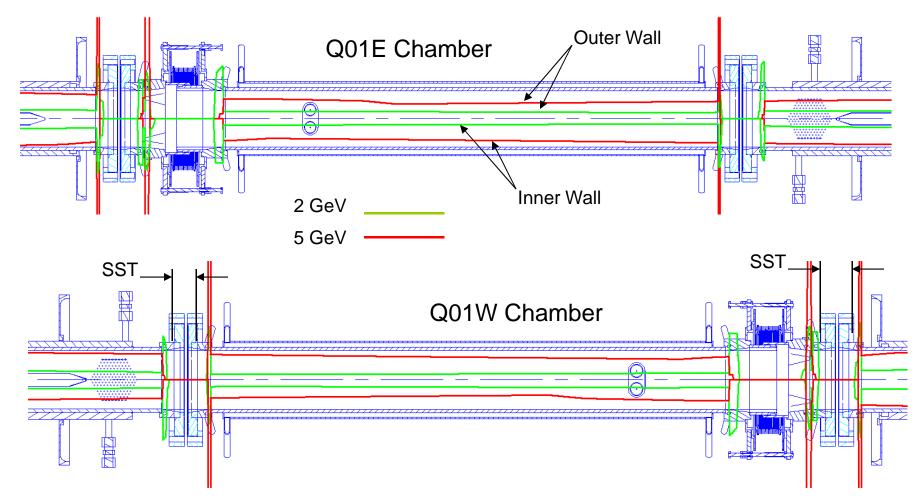
synch_powe	er_Outside.da	it ·				
Lattice: cerl/trunk/model/lat.bmad I_beam = 0.100000001490116 ! Amps/beam Epsilon_y = 2.999999901276418E-011 ! Vertical emittance						
Segment						
IX Name 1 OUTSIDE 2 OUTSIDE	S_seg (m) 0.100 0.200	X_seg (m) 0.030 0.030	P/len (W/m) 0.00E+00 0.00E+00	P/Area (kw/m^2) 0.0000E+00 0.0000E+00	P_tot (W) 0.0000E+00 0.0000E+00	Phot/sec (1/s) 0.0000E+00 0.0000E+00
3 OUTSIDE 4 OUTSIDE 5 OUTSIDE	0.300	0.030	0.00E+00 0.00E+00	0.0000E+00 0.0000E+00	0.0000E+00 0.0000E+00	0.0000E+00 0.0000E+00
4124 OUTSIDE 4125 OUTSIDE 4126 OUTSIDE 4127 OUTSIDE 4128 OUTSIDE 4129 OUTSIDE 4130 OUTSIDE	412.386 412.486 412.586 412.686 412.786 412.886 412.986	0.030 0.030 0.030 0.030 0.030 0.030	0.00E+00 0.00E+00 0.94E+02 0.13E+03 0.13E+03 0.13E+03	0.0000E+00 0.0000E+00 0.2907E+04 0.4255E+04 0.4181E+04 0.4132E+04 0.4058E+04	0.0000E+00 0.0000E+00 0.9418E+01 0.1336E+02 0.1331E+02 0.1331E+02	0.0000E+00 0.0000E+00 0.1116E+18 0.1583E+18 0.1577E+18 0.1577E+18
22889 OUTSIDE 22890 OUTSIDE 22891 OUTSIDE 22892 OUTSIDE 22893 OUTSIDE 22894 OUTSIDE 22895 OUTSIDE 22896 OUTSIDE 22897 OUTSIDE 22898 OUTSIDE	2288. 923 2289. 023 2289. 123 2289. 223 2289. 323 2289. 423 2289. 523 2289. 623 2289. 723	0.030 0.030 0.030 0.030 0.030 0.030 0.030 0.030 0.030	0.00E+00 0.00E+00 0.00E+00 0.00E+00 0.00E+00 0.00E+00 0.00E+00 0.00E+00 0.00E+00	0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00	0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00	0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00 0.0000E+00





SYNRAD Results - CesrTA Modification Example





SYNRAD used to ensure proper SR Masks were designed to shadow non-cooled components

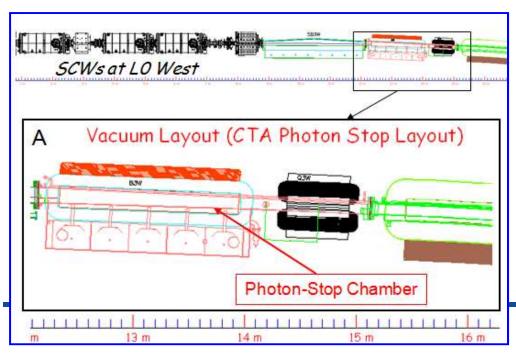


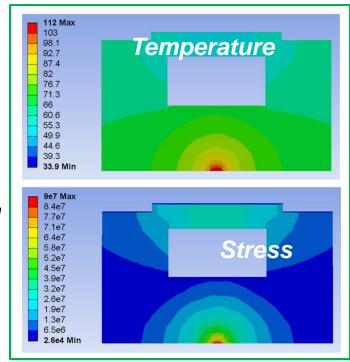


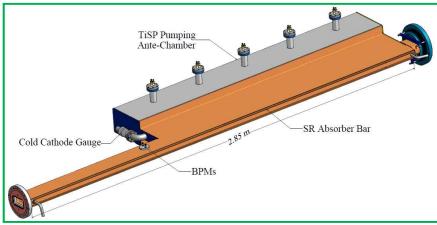
Thermal Stress Analysis – Example



- □ During CesrTA vacuum system conversion, a photon stopper chamber had to be designed to handle 40 kW of SR power generated from a string of six superconducting wigglers.
- ANSYS was used to calculate temperature rises and stress, at maximum power density of 6 W/mm², to verify safe operation of the chamber.





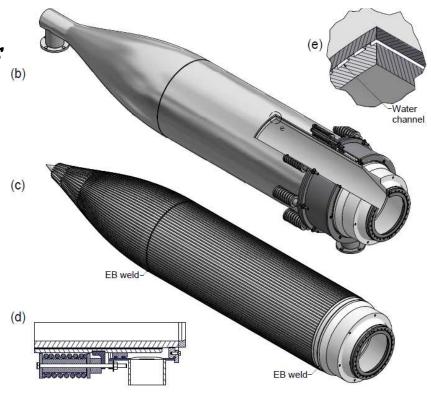


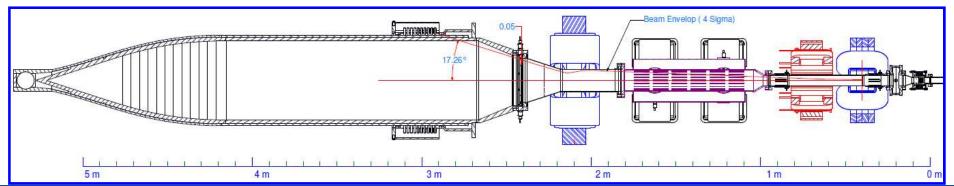


Electron Beam Dump - Another Example



- ☐ In Cornell's ERL prototype inject project, an 600-kW electron dump was designed and constructed.
- ☐ Aluminum (6062-T6) was chosen over copper due to its higher neutron generation threshold.
- ☐ A pair of quads used to enlarge the beam sized, and a modified Sectupole used to raster centroid of the beam.
- ☐ Cooling water channeled through small channels to enhance heat exchange.





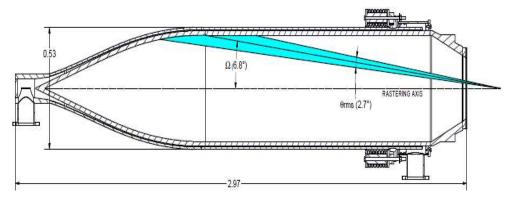


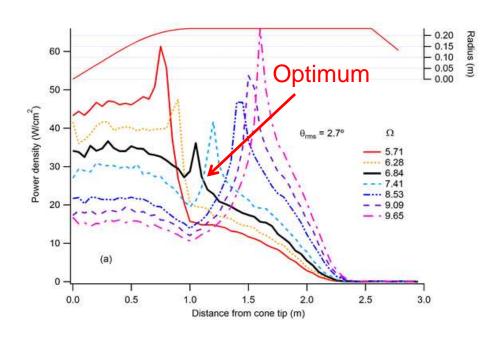


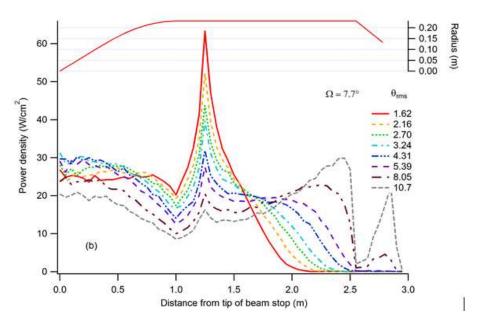
Simulate & optimize power deposition



☐ Geant4 (a toolkit for the simulation of the passage of particles through matter) was used to simulate electron beam interaction with dump body, and to optimize beam setup for even power deposition





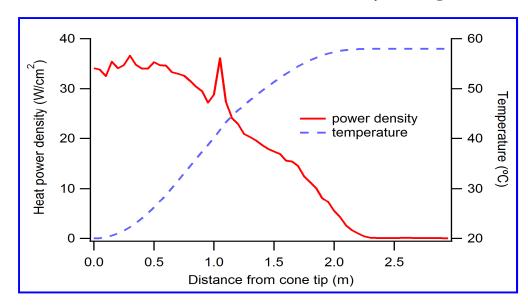


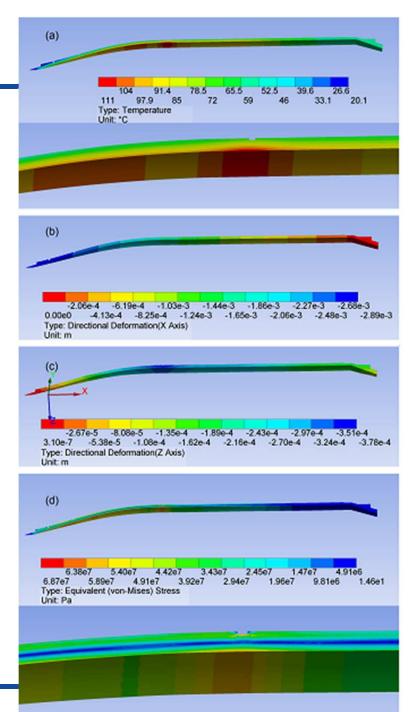




Dump Thermal Analysis

- □ After optimizing electron beam setting, ANSYS was used to calculate temperature distribution and analysis thermal stress, to ensure operational safety at design power level.
- ☐ Taking symmetry advantage, only one slice (16.4°) of the dump body needs to be modeled, to save computing time.





Pressure Profile Calculations/Simulations



- ➤ In accelerator vacuum system design, or/and in accelerator operations, knowledge of vacuum pressure distribution (or profile) is often needed for the following reasons:
 - → Optimizing pumping speed and capacity installed to keep average pressure and peak pressure under desirable level
 - → Understand impact of regional conductance limitation and local high gas load to the accelerator operations (such as beam lifetime, background to HEP detector, X-ray users)
- For almost all accelerator vacuum systems, molecular flow condition prevail.
- Though analytical method may work for very simple systems (such as round tubes), numerical approaches are usually used in simulating the pressure profile, with defined geometry, known pumping and calculated gas loads.



One-Dimensional Pressure Profiles



Since most accelerators and components have one dimension which is much bigger than the two others (length of the beamlines vs cross-section of the beampipe), one-dimensional mass-balance equation may be used:

$$V\frac{dP(x,t)}{dt} = Q(x,t) - S(x,t) \cdot P(x,t) + c(x,t) \cdot \frac{d^2P(x,t)}{dx^2}$$

At static states (which apply to most accelerator operation condition, where beam current varies slowly):

$$S(x) \cdot P(x) - c(x) \cdot \frac{d^2 P(x)}{dx^2} = Q(x)$$

where S(x), Q(x) are pumping speed and gas load, c(x) is specific gas conductance

In the literature, it is solutions to this equation that are found most often. Some of them are obtained analytically, others numerically.



Analytical Solution - Periodic System



- Consider a simple vacuum system of uniform cross section, with lumped pumps installed every L meters apart, no distributed pumping.
- Let A be the specific surface of the vacuum chamber, in cm²/m, and an uniform thermal outgassing rate, q in mbar·l/s·cm², we have

$$c \frac{d^2 P(x)}{dx^2} = -Aq \qquad \text{and by symmetry:} \qquad \begin{cases} \frac{dP}{dx}(x = L/2) = 0 \\ P(x = 0) = AqL/S \end{cases}$$

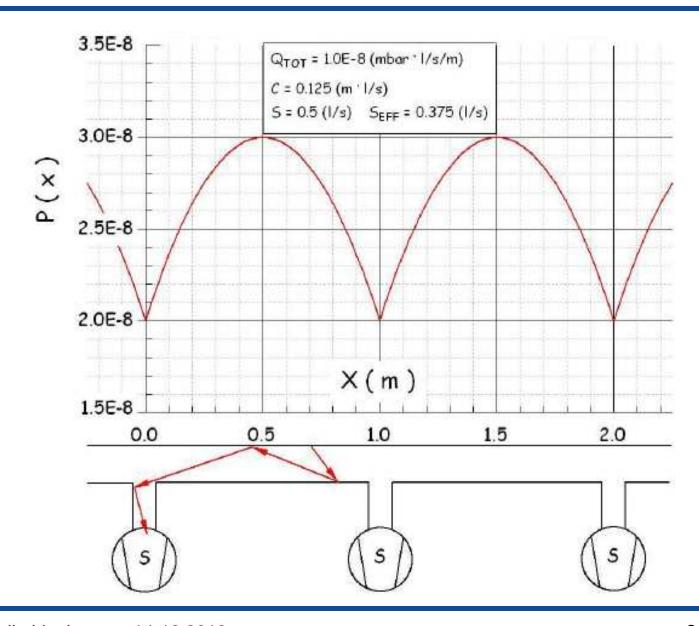
> The solution is:

$$P(x) = \frac{Aq}{2c} (Lx - x^2) + \frac{AqL}{S}$$



Analytical Solution - Periodic System Cont.







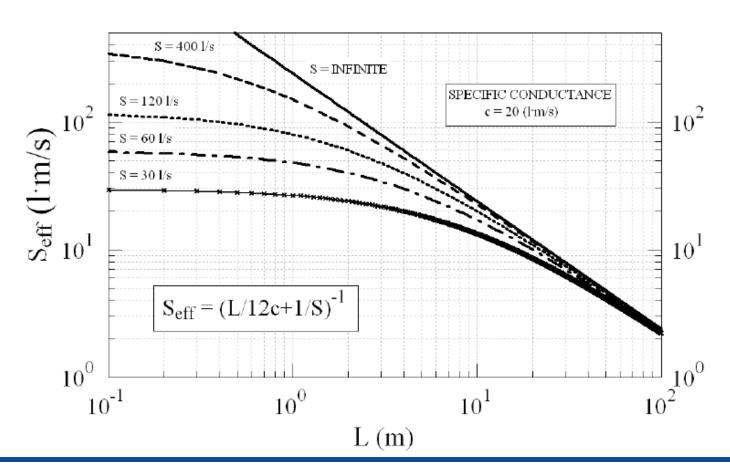


Analytical Solution – Periodic System Cont.



Average and maximum pressures are:

$$P_{avg} = AqL \left(\frac{L}{12c} + \frac{1}{S}\right) \equiv AqL \cdot \frac{1}{S_{eff}} \qquad \text{AND} \qquad P_{\max} = AqL \left(\frac{L}{8c} + \frac{1}{S}\right)$$







VACCALC: A Numerical Implementation



This solving technique is based on the finite-difference method, by 'slicing' vacuum system into N elements of equal length, Δx

$$S(x) \cdot P(x) - c(x) \cdot \frac{d^2 P(x)}{dx^2} = Q(x)$$

$$\frac{d}{dx} \left(c_i \frac{dP_i}{dx} \right) - S_i \cdot P_i + Q_i = 0$$



$$\frac{d}{dx}\left(c_i\frac{dP_i}{dx}\right) - S_i \cdot P_i + Q_i = 0$$

AND:

$$\frac{d}{dx}\left(c_{i}\frac{dP}{dx}\right) = \frac{(c_{i+1}-c_{i})P_{i+1} + (c_{i}-c_{i-1})P_{i-1}}{2\Delta x^{2}} - \frac{(c_{i+1}-c_{i-1}+2c_{i})P_{i}}{2\Delta x^{2}}$$

$$\frac{c_i + c_{i-1}}{2} P_{i-1} + \left\{ \frac{-\left(c_{i+1} + c_{i-1} + 2c_i\right)}{2} - s_i \Delta x^2 \right\} P_i + \frac{c_{i+1} + c_{i+1}}{2} P_{i+1} = q_i \Delta x^2$$

With proper boundary conditions, these linear equations can be solved for the pressure profile, P_{i}

Ref. "A Method for Calculating Pressure Profiles in Vacuum Pipes", Sullivan, SLAC, 1993



VACCALC Input



- Fach beampipe element is described by the following characteristics:
 - > Lumped or distributed values.
 - Length (m)
 - > Axial conductance (liters/sec)
 - Outgassing rate (nTorr-liters/sec)
 - Pumping speed (liters/sec)
- \triangleright Segment length ($\triangle x$) is specified for all elements
- > 10,000 segments max. per pipe





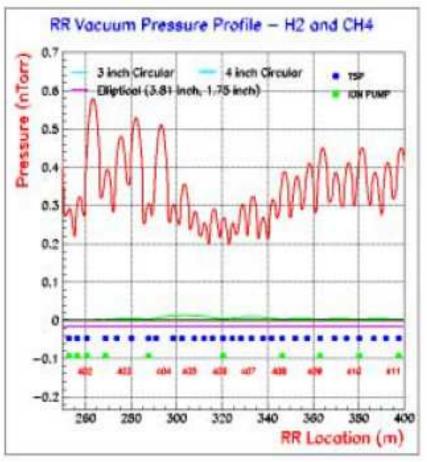
VACCALC Output



- > VACCALC produces an Excel Spreadsheet output file called "VACCALC.tsv" which includes the following:
 - 1. Pressure (nTorr) vs. Z (meters)
 - 2. Average Pressure along piping segment (nTorr)
 - 3. Axial Conductance (liters/sec-m) vs. Z (meters)
 - 4. Gas load (nTorr-liters/sec-m) vs. Z (meters)
 - 5. Pumping Speed (liters/sec-m) vs. Z (meters)

Example: K. Gounder, et al, "RESIDUAL GAS PRESSURE PROFILE IN THE RECYCLER RING", *Proceedings of the 2003 Particle Accelerator Conference*





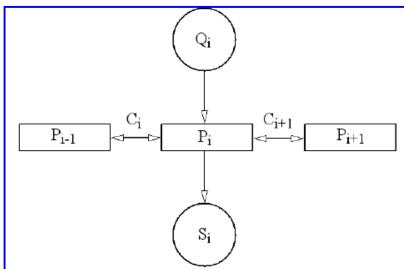




The Continuity Principle of Gas Flow



- Another way of solving the mass-flow balance equation is the so-called Continuity Principle of Gas Flow*, which can be stated after discretization of the vacuum system as shown.
- Each segment of the vacuum system
 is assigned its Si, Qi and Ci, and then
 its pressure Pi is obtained by solving the set of equations:



$$C_i(P_{i-1} - P_i) + C_{i+1}(P_{i+1} - P_i) + Q_i = S_i P_i$$

Three boundary conditions (BCs) were discussed in the reference(*):

1) Periodic BC; (2) Smooth BC; (3) Fixed BC

* Y. Li *et al.*, Calculation of pressure profiles in the CESR hardbend and IR regions, Proc. Int. Workshop on Performance and Improvement of e-e+ Collider Particle Factories, Tsukuba, 1999





The Continuity Principle of Gas Flow Cont.



Periodic BC:

$$\begin{cases} P_0 = P_n \\ P_{n+1} = P_0 \end{cases}$$
 then

$$\begin{cases} P_0 = P_n \\ P_{n+1} = P_0 \end{cases} \qquad then \qquad \begin{cases} C_1(P_n - P_1) + C_2(P_2 - P_1) + Q_1 = S_1 P_1 \\ C_i(P_{i-1} - P_i) + C_{i+1}(P_{i+1} - P_i) + Q_i = S_i P_i \\ C_n(P_{n-1} - P_n) + C_1(P_1 - P_n) + Q_n = S_n P_n \end{cases}$$

Smooth BC:

$$\begin{cases} P_0 = P_1 \\ P_{n+1} = P_n \end{cases}$$
 then

$$\begin{cases} P_0 = P_1 \\ P_{n+1} = P_n \end{cases} \qquad then \qquad \begin{cases} C_2(P_2 - P_1) + Q_1 = S_1 P_1 \\ C_i(P_{i-1} - P_i) + C_{i+1}(P_{i+1} - P_i) + Q_i = S_i P_i \\ C_n(P_{n-1} - P_n) + Q_n = S_n P_n \end{cases}$$

Fixed BC:

$$\begin{cases} P_0 = known \\ P_{n+1} = known \end{cases}$$
 then

$$\begin{cases} P_{0} = known \\ P_{n+1} = known \end{cases} \quad \text{then} \quad \begin{cases} -C_{1}P_{1} + C_{2}(P_{2} - P_{1}) + (Q_{1} + C_{1}P_{0}) = S_{1}P_{1} \\ C_{i}(P_{i-1} - P_{i}) + C_{i+1}(P_{i+1} - P_{i}) + Q_{i} = S_{i}P_{i} \\ C_{n}(P_{n-1} - P_{n}) - C_{1}P_{n} + (C_{n+1}P_{n+1} + Q_{n}) = S_{n}P_{n} \end{cases}$$

All these linear equations can be easily solved to obtain pressure profile, via so-called Substitute-Forward & Chase-Backward method, as described in the reference.

Arithmetic for Smooth BC



Continuity Principle of Gas Flow equations can be rewrite as:

$$a_i P_{i-1} + P_i + b_i P_{i+1} = d_i$$
 $(i = 1, 2, ..., n)$ (A)

$$\begin{cases} a_i = -C_i/(C_i + C_{i+1} + S_i) \\ b_i = -C_{i+1}/(C_i + C_{i+1} + S_i) \\ d_i = Q_i/(C_i + C_{i+1} + S_i) \end{cases} \begin{cases} a_1 = 0 \\ b_1 = -C_2/(C_2 + S_1) \\ d_1 = Q_1/(C_2 + S_1) \end{cases} \begin{cases} a_n = -C_n/(C_n + S_n) \\ b_n = 0 \\ d_n = Q_n/(C_n + S_n) \end{cases}$$

Forward-Substitute (solving for P_i in **i**th equation in equations (A) and then

substituting solved P_i into (i+1)th equation in equations (A), an so forth, from i=1 to i=n)

$$\begin{cases} P_{i} = d_{i}^{*} - b_{i}^{*} P_{i+1} & (i = 1, 2, ..., n-1) \\ P_{n} = d_{n}^{*} & (B) \end{cases}$$

$$\begin{cases} b_1^* = b_1 \\ d_1^* = d_1 \end{cases} \qquad \begin{cases} b_i^* = b_i / (1 - a_i b_{i-1}^*) \\ d_i^* = (d_i - a_i d_{i-1}^*) / (1 - a_i b_{i-1}^*) \end{cases} \quad (i = 2, 3, ..., n-1) \qquad & \qquad & \qquad & \qquad & \qquad & \qquad & \\ d_n^* = (d_n - a_n d_{n-1}^*) / (1 - a_n b_{n-1}) \end{cases}$$

The pressure profile is now easily obtained by 'chase-back' of equation (B)

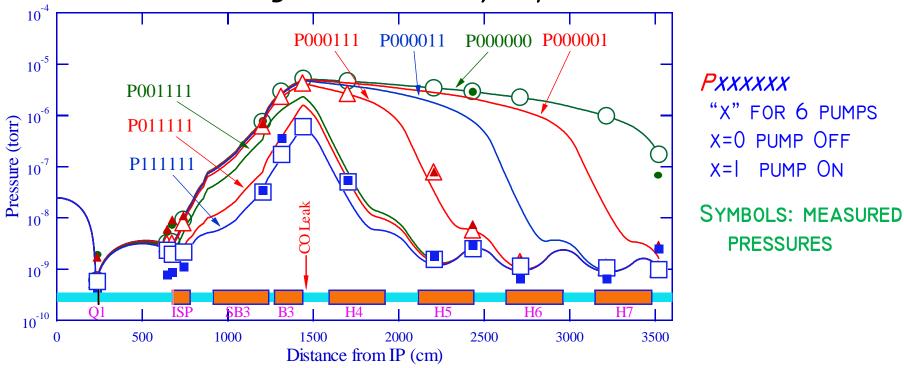
Implementation in IGOR Pro. (ICM Prototype Beamline Pressure Profile)



Application – Background of HEP Detector



In CESR/CLEO HEP II operations, an experiment was conducted to probe the HEP detector background sensitivity to pressure distribution



- In the experiment, a CO gas was introduced to create a 'pressure bump", and ion pumps (2 LPs, 4 DIPs) were turned off sequentially to spread the bump. A probe electron beam was sent through the bump to measure detector background.
- Pressure profiles were calculated and compared to the measured pressures, with ion pump speed's pressure dependence taking into account.
- The results helped design of background masks for the CESR/CLEO III upgrade.





Application – Background of HEP Detector 2

1.0

0.8

0.6



- * Gas load Q -- dominated by the CO leak, 1.6x10⁻⁵ torr·liter/s
- * Conductance -- calculated using MOLFLOW
- * Pumping Speed

TiSPs --
$$S_{max} \bullet F_{sat}$$
; S_{max} -Plenum Conductance, F_{sat} - Saturation factor

Profile with

 $f(P_{i-1})$

DIPs -- $S_{max} \cdot f(P)$, Pressure dependent pumping speed

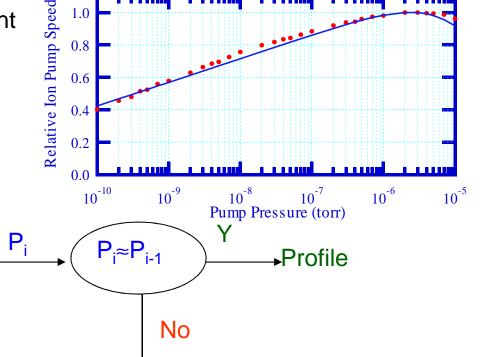
* Self-consistent iteration

Profile with

f(P) = 1

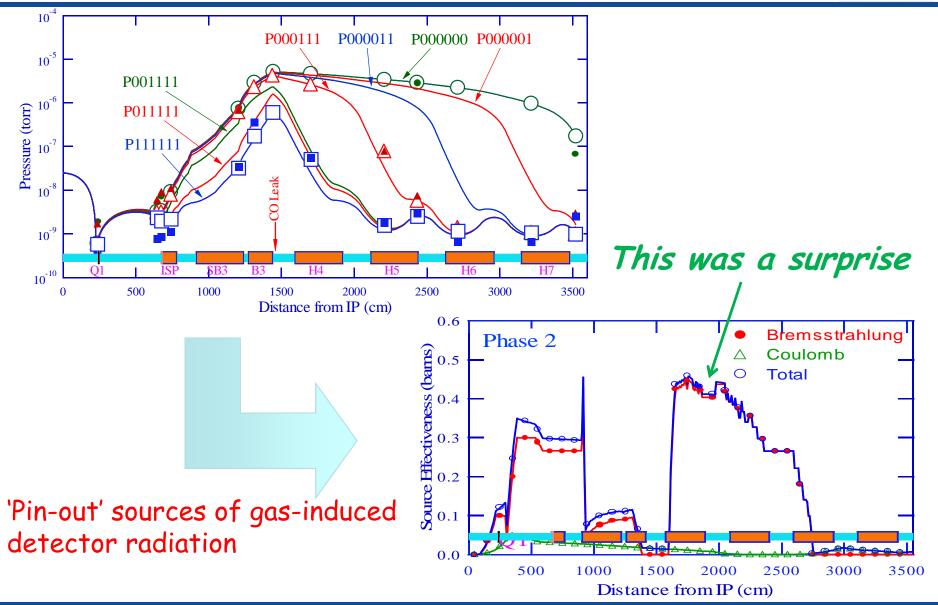
Table 3. DIP Pumping Speed Parameters

DIP Name	Max. Pumping Speed, l/s/m			
B3E	55			
H4E	85			
H5E	100			
H6E	120			
H7E	120			



Pressure Manipulations and Calculations





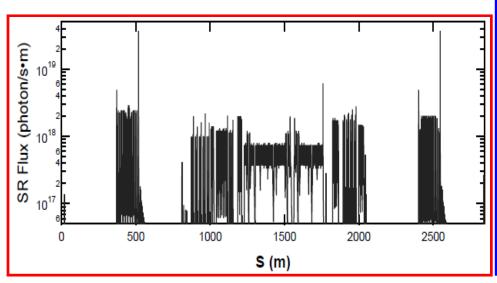


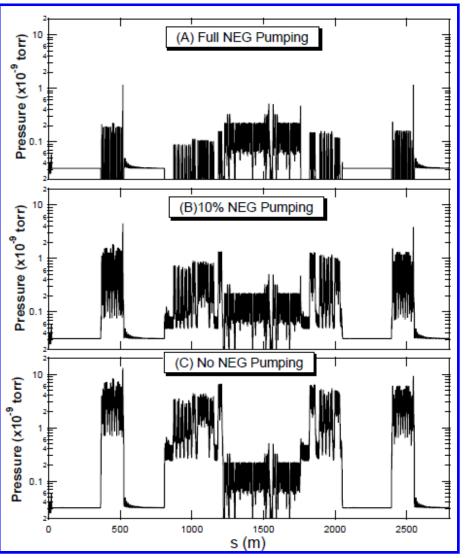


Application - Cornell ERL Vacuum Design



- ➤ In conceptual design of Cornell ERLbased light sources, pressure profile calculations were carried out to ensure adequate vacuum pumping (Ion pumps and NEG strips.).
- > SYNRAD provided SR flux for 100 mA electron beam at 5 GeV.
- Thermal outgassing and SR-induced gas-load (SR yield of 10-6 mol/ph) included in calculation.









Pressure Profile Calculation — Limitations



- Results from one dimensional pressure profile calculations should be used with caution, though they are valuable design tools. It is most suitable for vacuum system with true uniform cross-section.
- ☐ The accuracy of the results heavily depends on the calculation of the specific gas conductance. Even for simple cross sections (such as round and rectangular), often the used conductance is over-estimated, as the 'beaming' effect of continuous 'slices' of 'elements' is not considered.
- For complex beam pipe cross sections, Monte-Carlo methods are used to compute gas conductance.
- Another source of errors is in the estimation of gas loads, particularly the dynamic gas load, such as SR-induced desorption. Though it is relatively straight forward in calculating SR flux impinging on walls, the desorption yield is 'history' and spatially dependent.

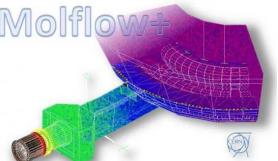


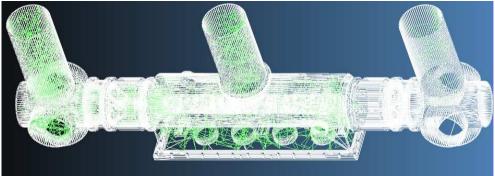
MOLFLOW+ - Test Particle Monte-Carlo



- The TPMC method consists of calculating a large number of molecular trajectories in order to get a picture of a rarefied gas flow.
- Walls of a vacuum system are divided into planar facets. Test particles 'bounce'
 off facets with a cosine distributions, and continue be tracked until they exit
 the system, or into pumps. The facets can be assigned as pumps (with a sticking
 coefficient) or as gas sources.
- TPMC is best for computation of molecular flow conductance, but it can also generate 3D pressure profiles.

 Though the author (Roberto Kersevan) continues to improve the user-interface, MOLFLOW+ is still very difficult to use, and extremely time-consuming in initial setup.





REF: R. Kersevan and J.-L. Pons, JVST A 27(4) 2009, p1017







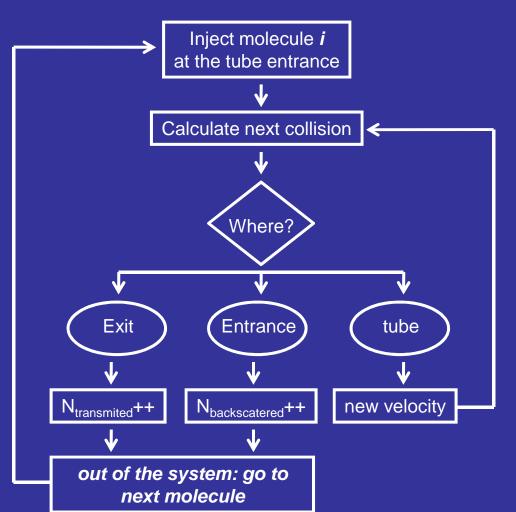
The Following Slides are Courtesies of Roberto Kersevan of CERN, the Author and the developer of MOLFLOW and MOLFLOW⁺

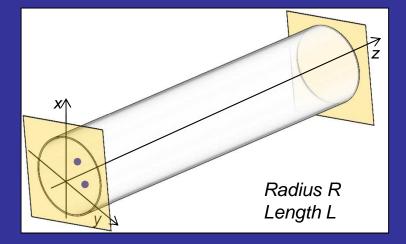






Calculate the molecular transmission probability of a tube.





Transmission probability:

$$\alpha = \frac{N_{transmited}}{N_{total}}$$

backscattering probability:

$$eta = rac{N_{backscattered}}{N_{total}}$$

Standard deviation:

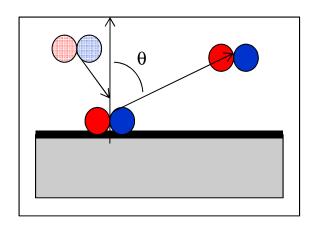
$$\sigma_{\alpha} = \sqrt{\frac{\alpha \cdot (1 - \alpha)}{N_{total}}}$$

How Molecules Interact with a Wall



Adsorption

If adsorption time is long the molecule is pumped (getters, cold surfaces)



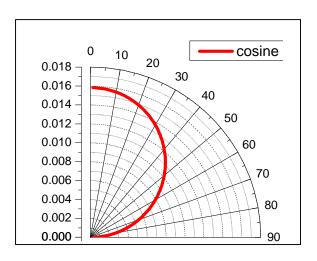
Desorption

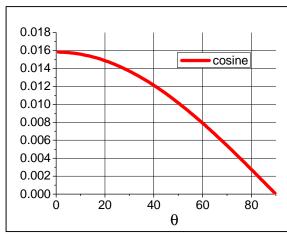
If adsorption time is short $(\sim 10^{-11} \text{ s for physisorbed CO}, N_2, O_2).$

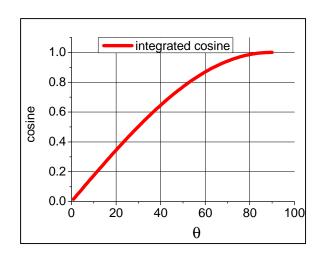
The angle of desorption, θ , is independent of the incident angle.

The "desorbed flux" follow the cosine law:

$$I(\theta) = I_0 \cos^n \theta$$
 $n \ge 1$







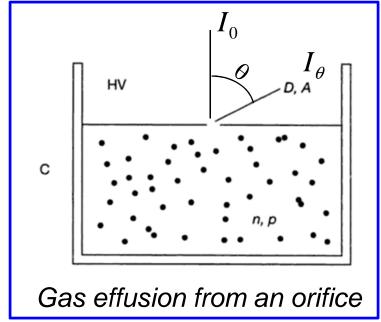


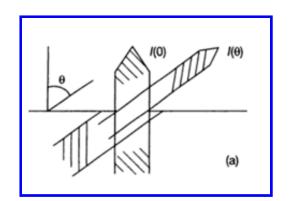
Knudsen's Cosine Law — Effusion



- □ Considering gas molecules exiting from on thin orifice (with area A). Assuming a much better vacuum above the orifice and a gas density below is in molecular flow region.
- ☐ The molecular flux (I_0) in the direction normal to the orifice is proportional to the density and the orifice area A.
- Assume that molecules exit the orifice isotropically, the flux (I_{θ}) at angle θ is also proportional to the density and a projected orifice areas $A \cdot \cos \theta$. Thus, we have the Knudsen's cosine law of effusion:

$$I_{\theta} = I_0 \cos \theta$$





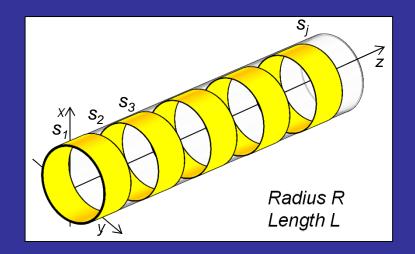


Calculate the transient pressure profile in a tube.

Define the sectors where the pressure must be computed (pressure counters);

Define sampling time (time for which we want to get the pressure profiles):

$$t_{\text{sampling}}[]=\{t_1,t_2,\ldots t_k\}.$$

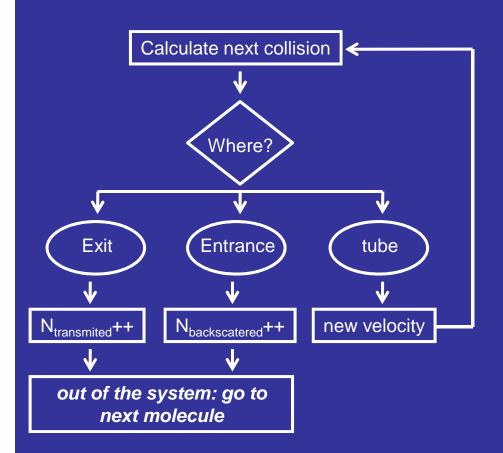


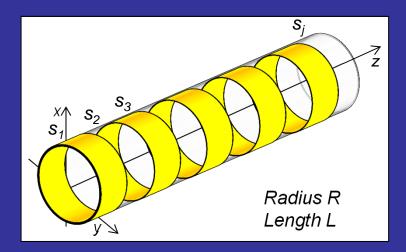
Inject molecules, calculate next interaction, (as for the transmission probability case), and for each time $t_{sampling}$ [] update pressure counters.

$$p_i = \frac{N_{sim,i}f}{V_i}k_bT, \text{ f is the scaling factor } f = \frac{N_{real}}{N_{sim,total}}$$



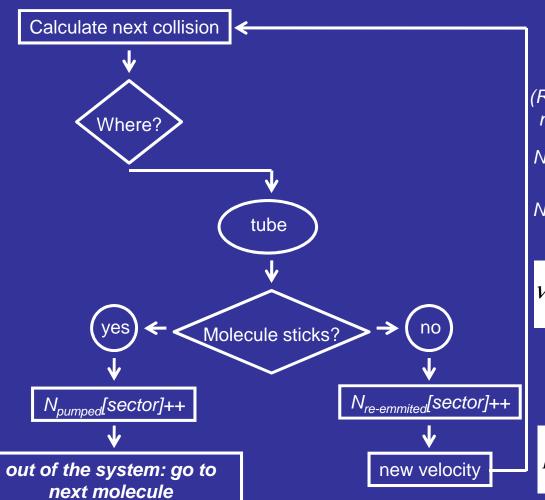
If surfaces have sticking probability? (getters, cold surfaces)







If surfaces have sticking probability? (getters, cold surfaces)



Molecule sticks? If Rnd() < s the molecule sticks Else re-emmited

(Rnd() is a function to generate random numbers uniformly distributed in [0,1]

N_{pumped}[sector] -> gives the distribution of the molecules pumped

N_{re-emmited}[sector] -> gives the pressure profile (via the impingement rate)

$$v[\text{sector}] = \frac{N_{re-emmited}[\text{sector}]}{N_{total} \cdot A[\text{sector}]} \cdot \frac{Q}{kT}$$

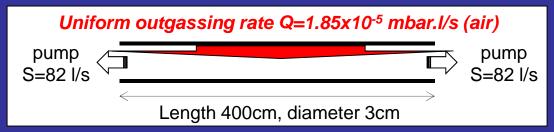
$$p[\text{sector}] = \frac{4kT}{v_a} v[\text{sector}]$$

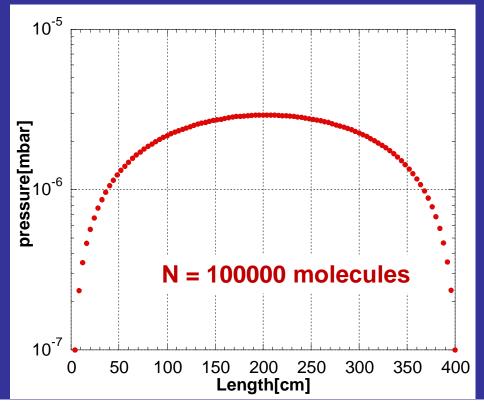
$$p[\text{sector}] = \frac{4Q}{v_a} \frac{N_{re-emmited}[\text{sector}]}{N_{total} \cdot A[\text{sector}]}$$



The Test Particle Monte Carlo: Examples.

Steady state pressure profile in a tube

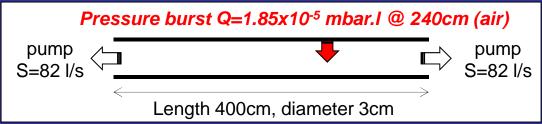


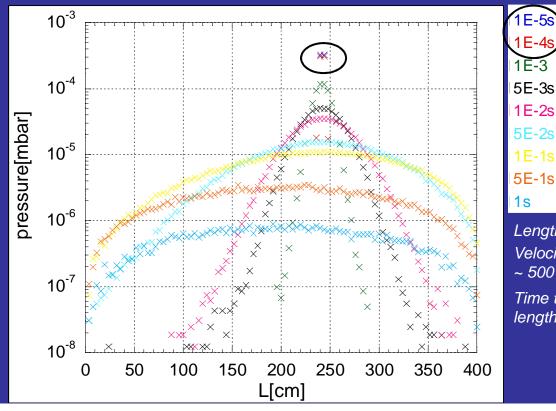




The Test Particle Monte Carlo: Examples.

Transient pressure profile after a pressure burst in a tube





Length of sector = 4m/100 Velocity air molecule at 25°C ~ 500 m/s

Time to fly along a sector ~ length / velocity = 8x10⁻⁵ s



MolFlow+

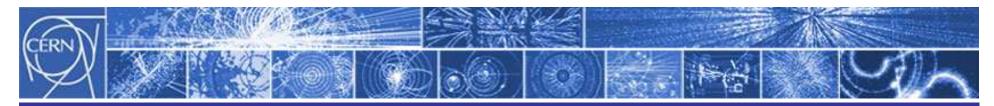
Written by Roberto Kersevan (former leader of the Vacuum group at ESRF; since July 2009 at ITER, now at CERN)

Developed since 1991, (started at CERN), in Turbo Pascal. used mainly in accelerators laboratories (Diamond Light Source, BNL, Elettra, Alba, Sesame, ASTeC, FermiLab, Cornell, and more). Old versions not very user friendly...

New version since 2008: written in C/C++ under Windows XP/ OpenGL, fast, optimized for multi core CPUs (parallelization)... user friendly graphic interface, but lacks a serious manual...

Geometries can be imported in 3D-CAD format (.STL, common to the main CAD programs)

The program can be obtained directly from the author: Roberto Kersevan <roberto.kersevan@cern.ch>



MolFlow+

Procedure:

3D CAD drawing

Import into Molflow+ (.STL)

Attention: version 2.1 only accepts ASCII type .STL files

Configure simulation model:

Define facets, desorption, pumping, opacity, etc

Where the user spend more time: the .STL file loads surfaces built with triangles. The user must "collapse" some of this triangles by groups in order to define the usefull facets for the simulation. Less facets also means faster runs!

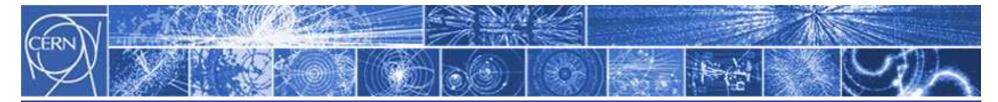
Define outputs:

Profiles: pressure, angular distributions, formulas.

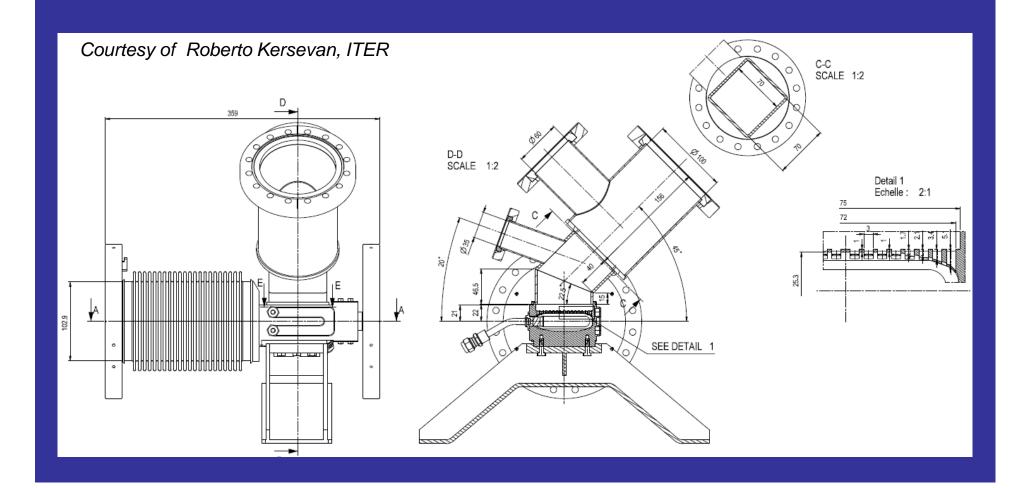
Pressure and angular profiles can be plotted for "real" facets or for "virtual" facets, (imposed to the model just for this purpose). For example, if we want to plot the pressure along the transversal plane of a tube.

RUN

Practical results within a few seconds to hours, depending on geometry. (1,550,000 hits/s in a 2.4GHz dual core CPU)

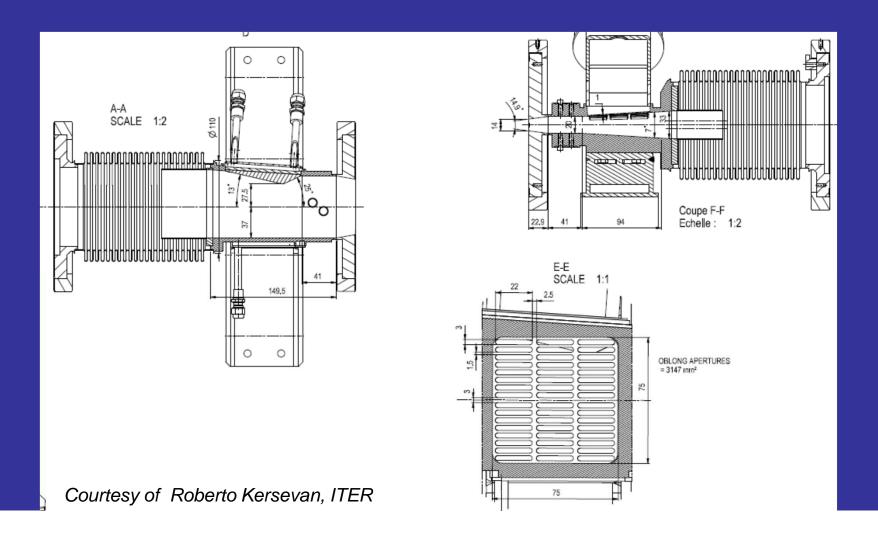


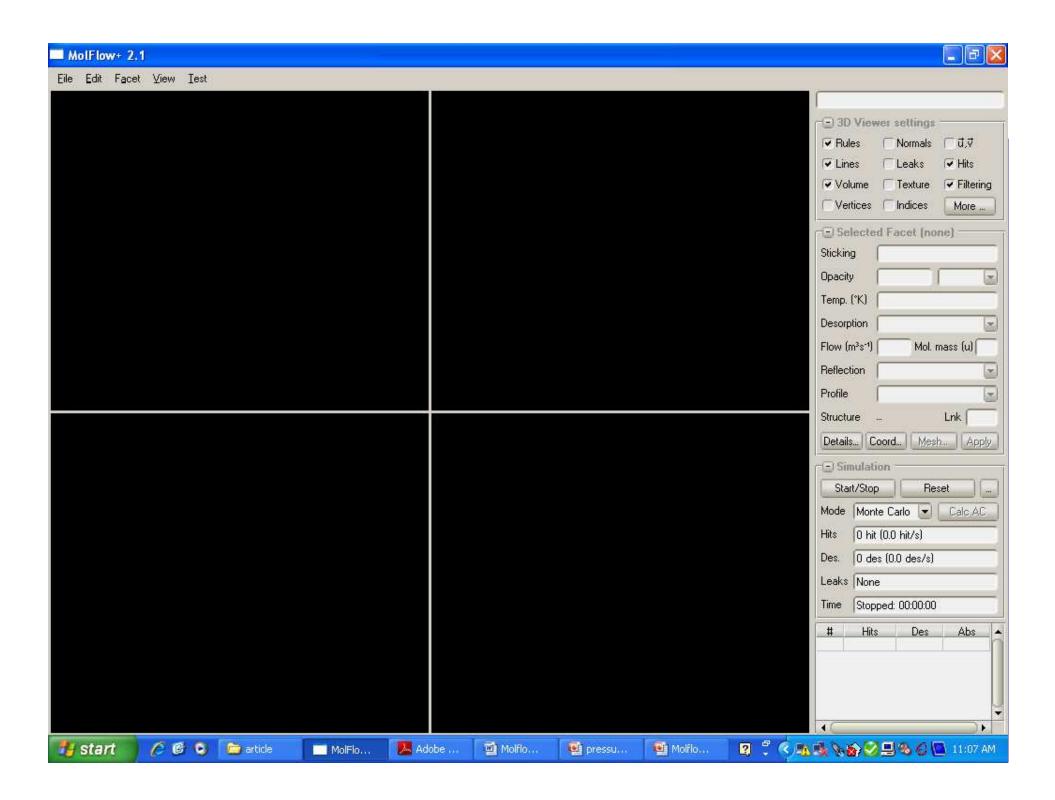
Example with MolFlow+: pumping port at ESRF

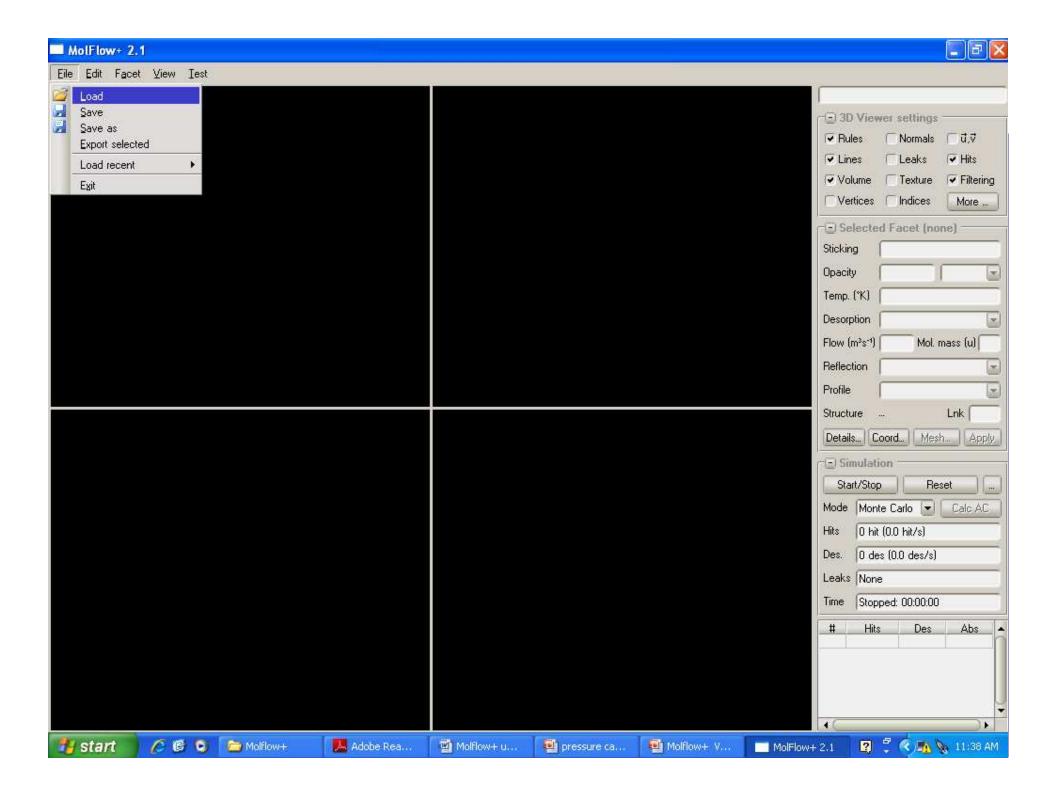


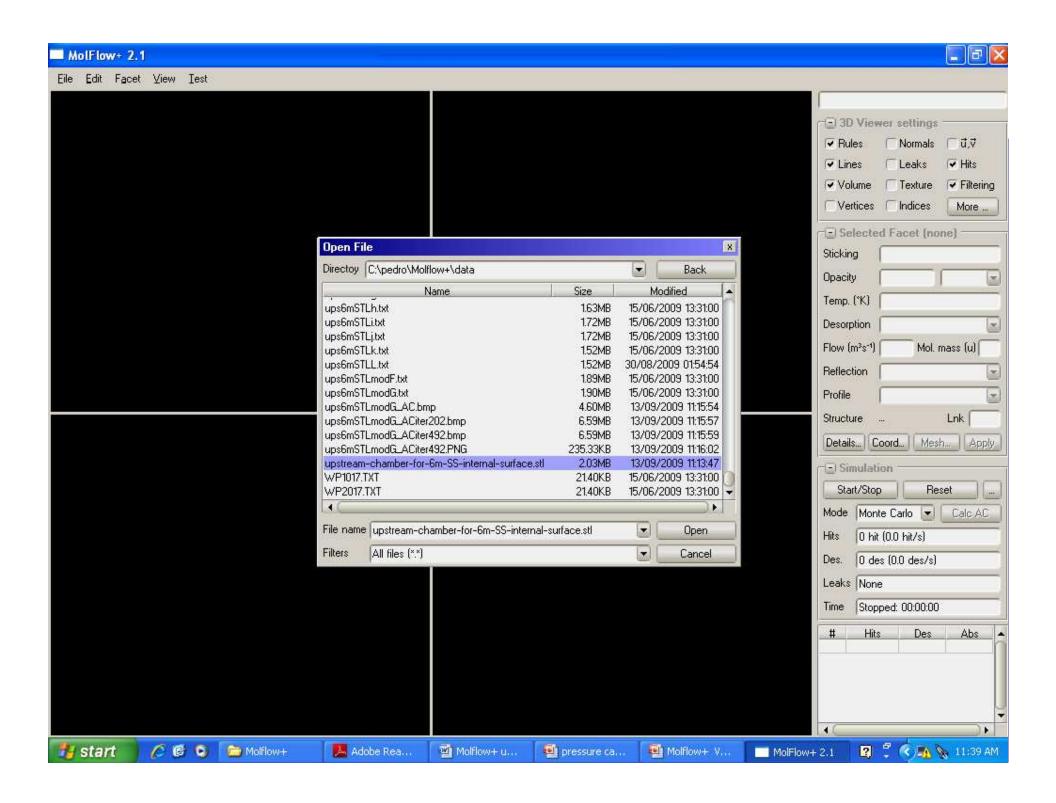


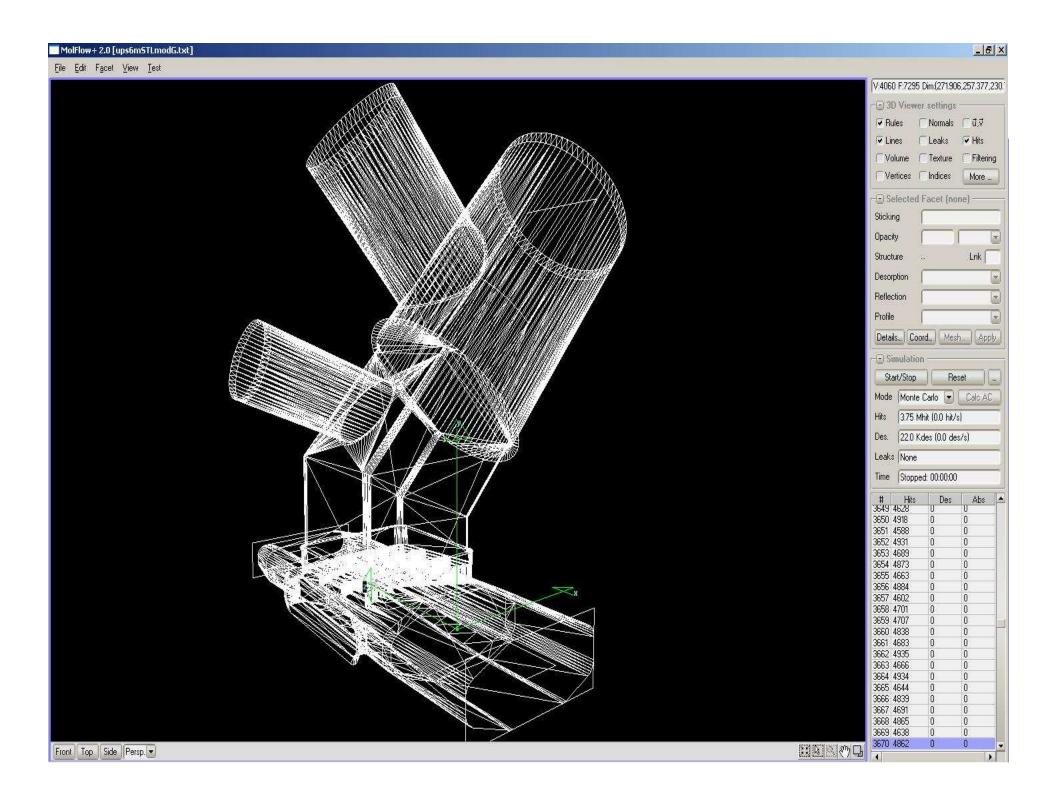
Example with MolFlow+: pumping port at ESRF

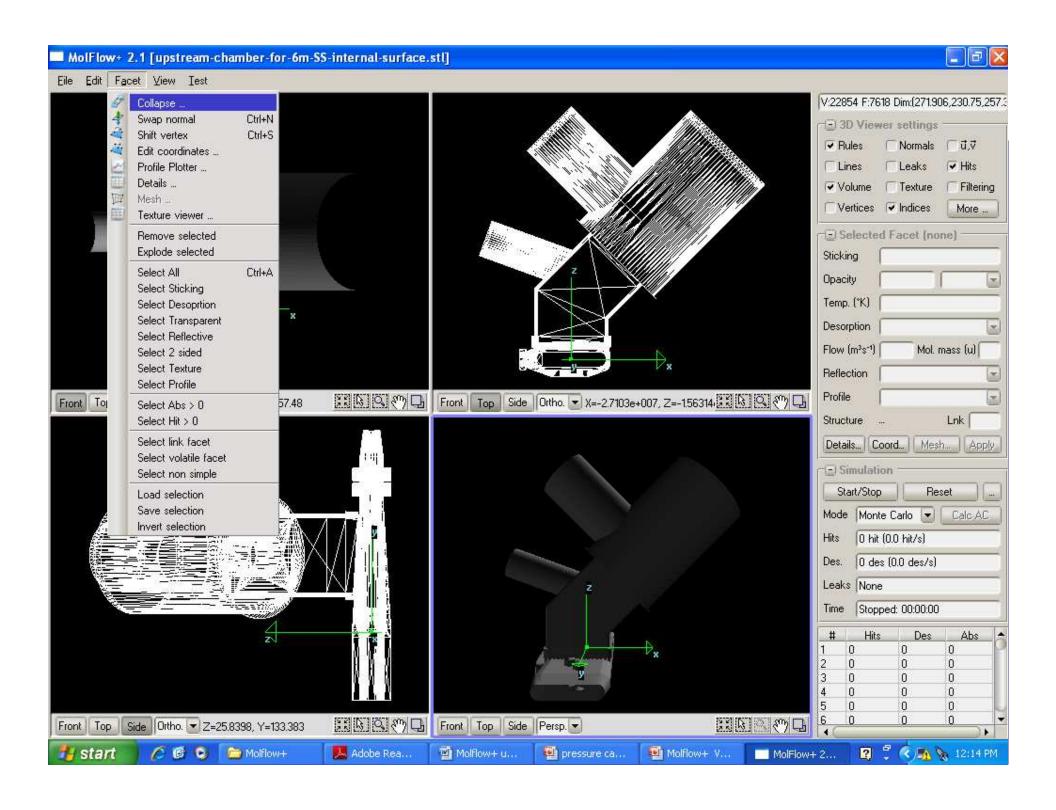


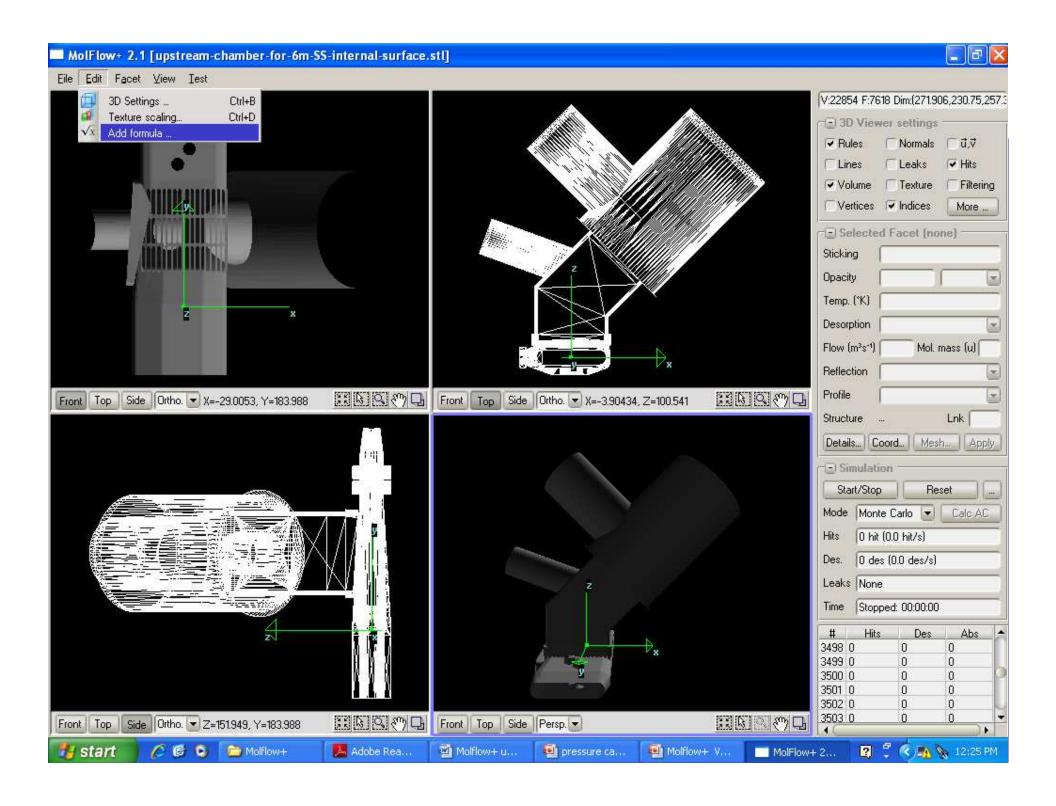


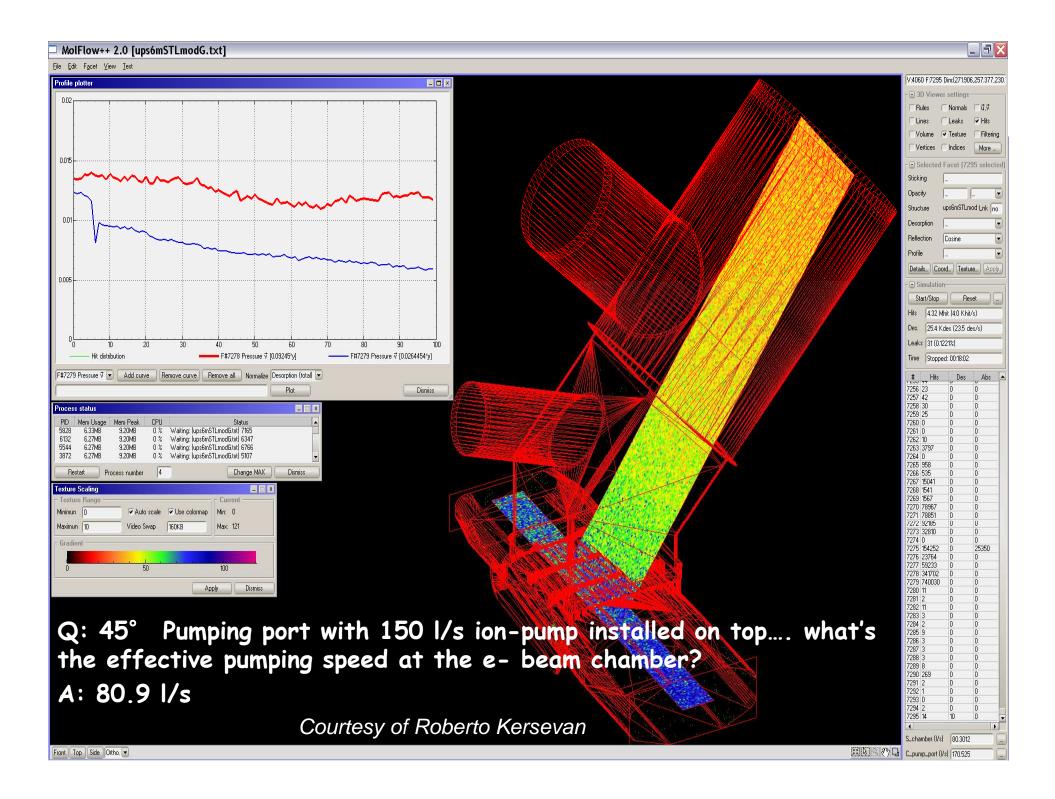














The Test Particle Monte Carlo

Summary:

Simple physical basis: rectilinear movement of molecules in UHV, cosine like desorption, molecules move independently from each other.

Flow charts for the simulation are simple: do not require expert programmers to write a code for a dedicated simulation. (to work with 3D CAD files it's another story...)

Both steady state and transient regimes can be simulated with accuracy in 3D

It is a statistical method: accuracy depends on the number of molecules tracked

Steady state simulation of 3D complex geometries, loaded from CAD files, can be done with MolFlow+ in a user friendly environment.

Transient simulation of 3D complex geometries, loaded from CAD files, can be done with FEM PROGRAMS, (slow), or with your own code...

Molflow 'History'

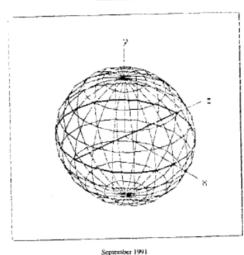
- Developed since 1991 (R. Kersevan)
- Turbo Pascal, 13.000 lines of code
- Used by:
 - Diamond Light Source
 - BNL
 - Elettra
 - Alba
 - Sesame
 - ASTeC
 - FermiLab
 - Cornell
 - •
 - CERN



ST/M-91/17

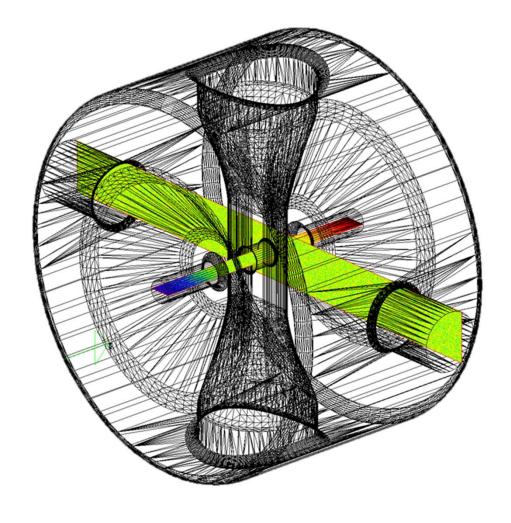


Roberto Kersevan



SPICEOTRONE TRIESTE

Molflow+



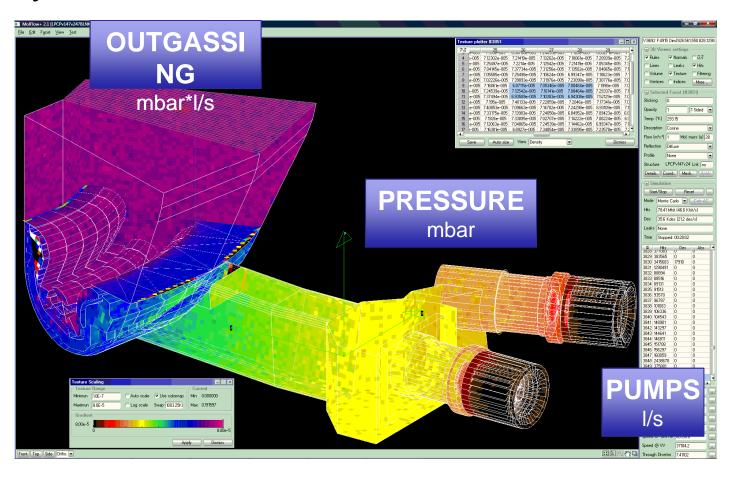
UHV

Synrad+

Synchroton Radiation

Molflow+

"Friendly units"



Multiple outgassing

Synrad+ AND Molflow+

